



CONSIGLIO NAZIONALE DELLE RICERCHE
Istituto di Fotonica e Nanotecnologie

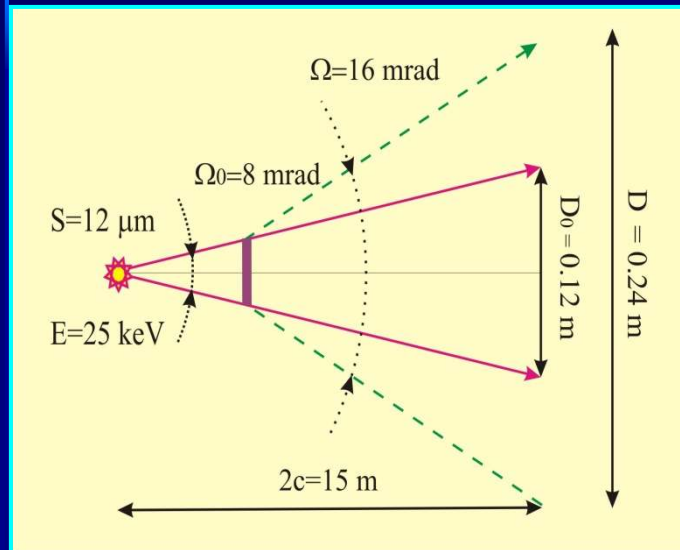
Studio di ottiche in riflessione e rifrazione per l'ottimizzazione del fascio Thomson

I.Bukreeva, A.Cedola, M.Fratini, A.Sorrentino,
S.Lagomarsino

Geometry of the optical system



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Source

Source:	TS
Size of the source:	12 x 12 μm
Wavelength:	0.5 \AA
Divergence Ω	8 mrad
Distance source – detector:	15 m
Area of illumination	0.12 m

Goal

**Increase divergence of the source and therefore
the area of illumination up to 0.24 m**

X-ray reflective optics basic rules

Critical angle

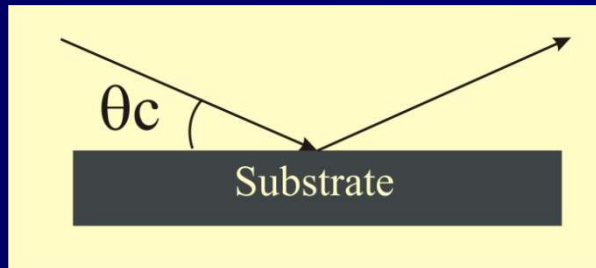
The *index of refraction* for x-ray radiation is

$$n = 1 - \delta - i\gamma \quad \gamma < \delta \ll 1 \rightarrow \text{Re}(n) < 1$$

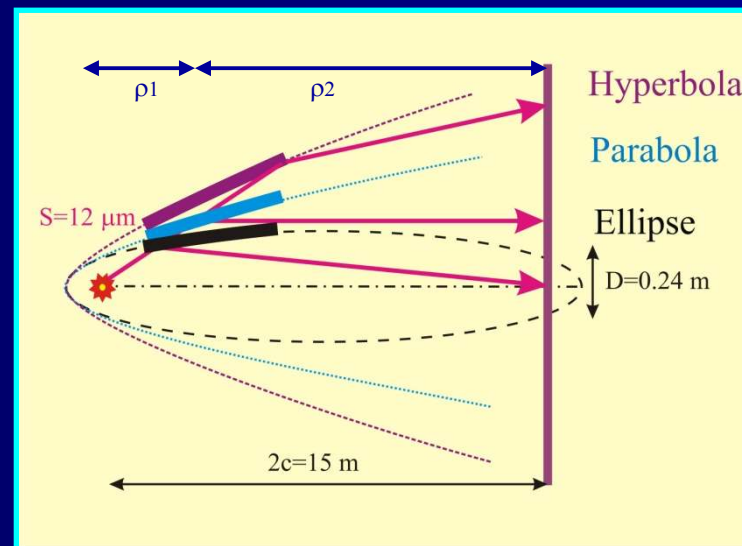
↓
Total reflection below a critical angle

$$\theta_c = (2\delta)^{1/2} \sim \lambda$$

$$\theta_c (Pt, \lambda = 0.05 \text{ nm}) = 3.4 \text{ mrad} \ll \Omega = 8 \text{ mrad}$$



Geometry of grazing incidence optics



Ellipse

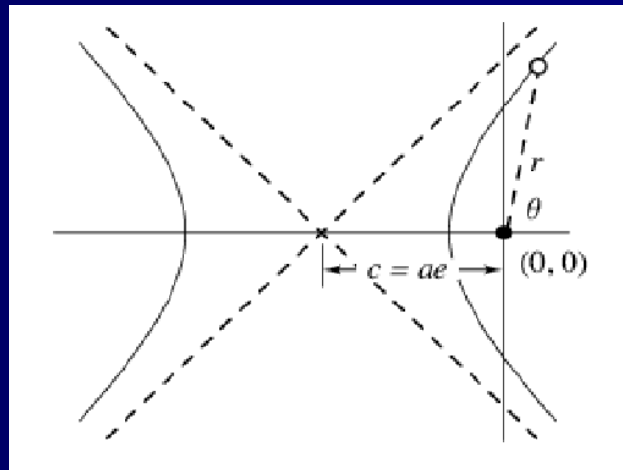
$$M = D/S \approx \rho_2 / \rho_1 = 2 \cdot 10^4 \Rightarrow \rho_1 \approx 7.5 \cdot 10^{-4} \text{ m}$$

Parabola

$$\Phi_{\text{max}} = 2\theta_c \approx 7 \text{ mrad}$$

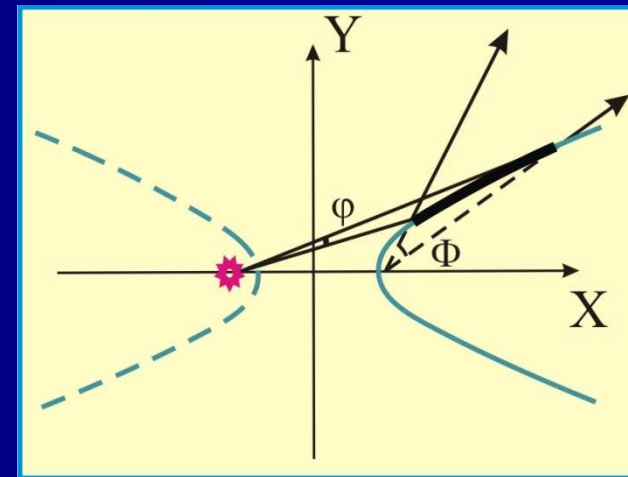
$$L \gg 1 \text{ m}$$

Hyperbolic reflecting mirror



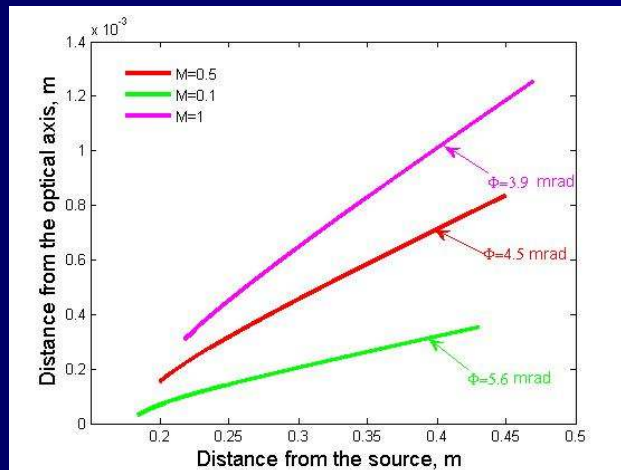
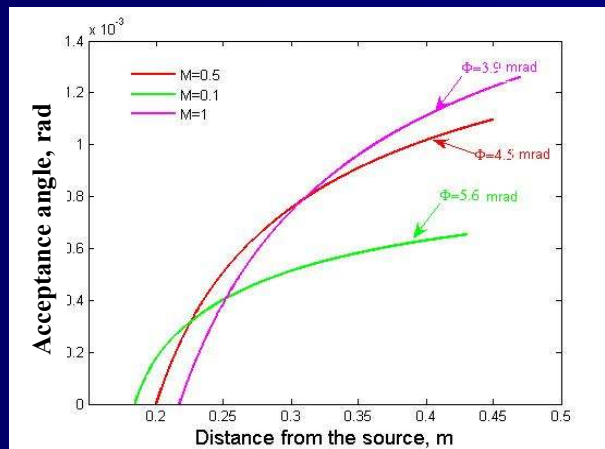
In polar coordinates centered at a focus,

$$r = \frac{a(e^2 - 1)}{1 - e \cos \theta}$$



All x-rays emitted from the source and reflected from the hyperbolic surface give a divergent beam having a secondary imaginary source

Hyperbolic reflecting mirror



Length of the mirror $L=0.25$ m
material Pt

Critical angle 3.4 mrad

Eccentricity

$$e = 1 + \frac{1}{2}\theta_c^2 M$$

Acceptance angle increase with increase of the eccentricity e

but

divergence Φ of the reflected beam decrease therefore

$$e_{\text{opt}} = 1 + \frac{1}{2}\theta_c^2 M, \quad M = 0.5$$

Acceptance angle $< \theta_c = 3.4$ mrad

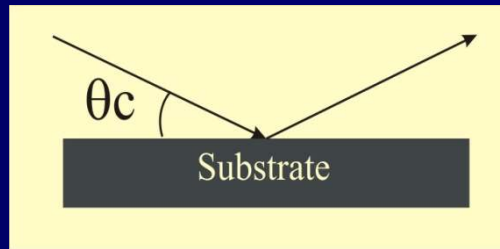
$\beta_{\text{max}} \sim 1$ mrad $\ll \Omega = 8$ mrad

Short-period multilayers

Critical angle

$$\theta_c = (\delta)^{1/2} \quad \varepsilon = 1 - \delta + i\gamma \quad \gamma \ll \delta \ll 1$$

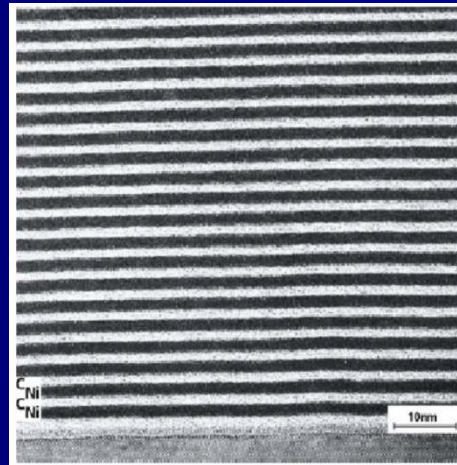
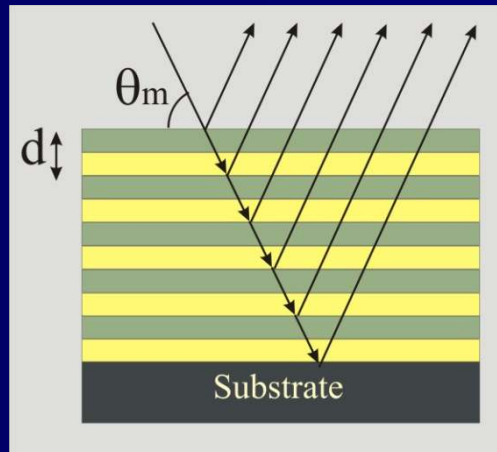
$$\theta_c (\text{Pt}, \lambda = 0.05 \text{ nm}) = 3.4 \text{ mrad} \ll \Omega = 8 \text{ mrad}$$



Multilayer mirror

$$2d \sin(\theta_m) = m\lambda \quad \longrightarrow \quad d = 2-3 \text{ nm}$$

$$\theta_1 = 8-12 \text{ mrad}$$



Ni / C d=3.15 nm

*R. Dietsch, S. Braun, T. Holz, H. Mai,
R. Scholz, L. Brugemann
"Multilayer x-ray optics for energy
E > 8 keV and their application in x-ray
analysis" SPIE*

Short-period multilayers

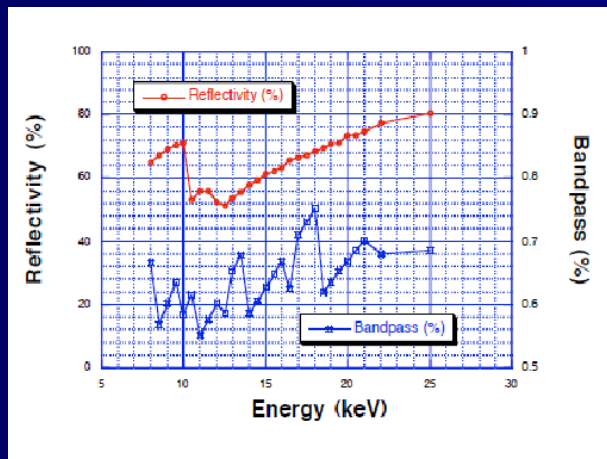
Multilayer (0.965 nm WSi₂)/(1.005 nm Si)
d=2 nm

$\theta_1=12.5$ mrad

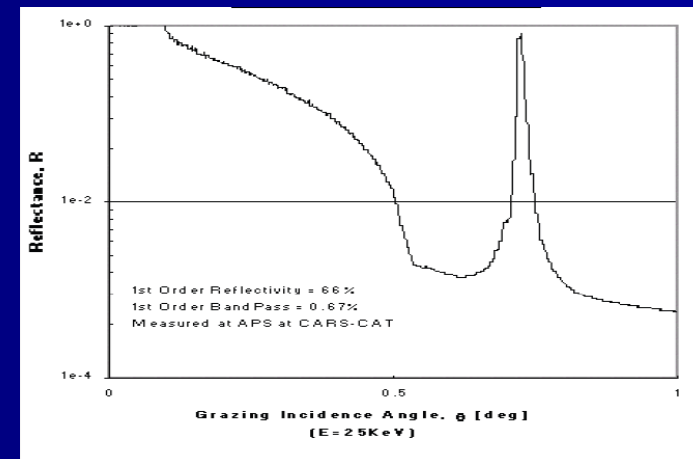
Advantage of WSi₂/Si multilayer

High temperature and radiation load stability

*C.Liu, R.Conley, A.T.Macrander, T.Grabner,
Ch.Morawe,C.Borel, E.M.Dufresne,
"Small-d-spacing WSi₂/Si narrow bandpass multilayers"
Proc. SPIE, Vol. 5537, 154 (2004)*

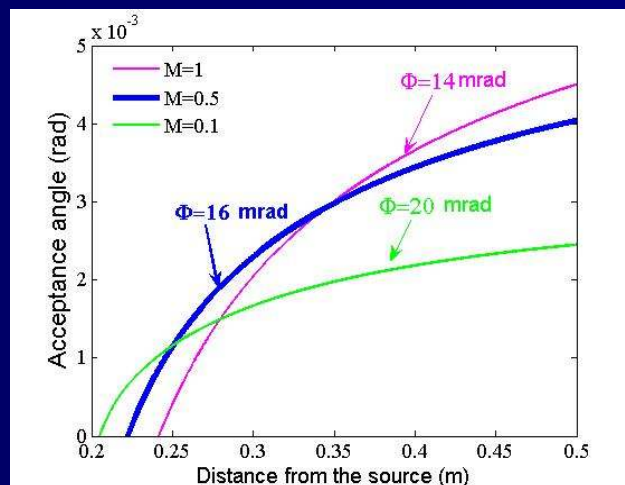
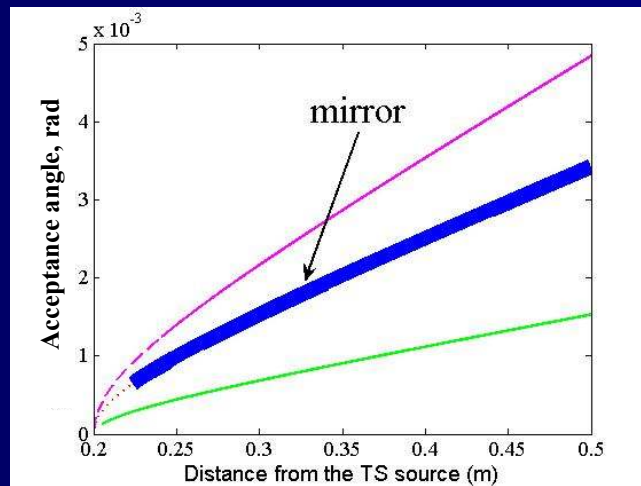


Simulated reflectivity and bandpass for
WSi₂/Si (d=2 nm) x 300 multilayer
R (E=25 keV) = 80 %



Reflectivity scan carried out at the
ChemMatCARS-CAT of the APS at 25 keV
R(E=25keV)=66%, bandpass 0.67%

Hyperbolic reflecting mirror



Length of the mirror $L=0.25$ m

WSi2/Si multilayer

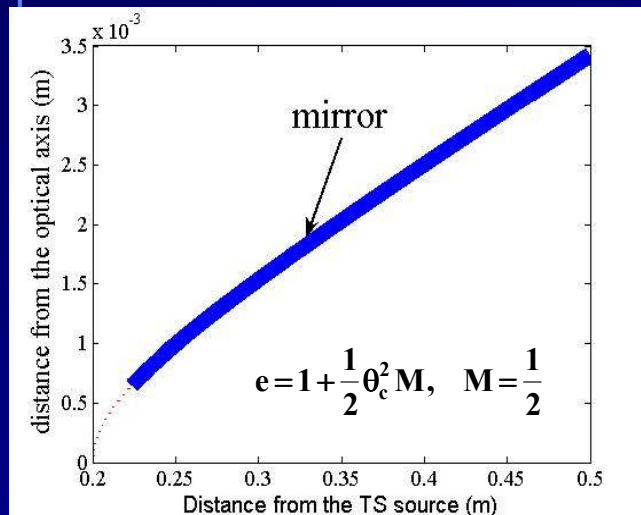
$\theta_1=12.5$ mrad

Eccentricity $e = 1 + \frac{1}{2}\theta_1^2 M$, $M = 0.5$

Acceptance angle

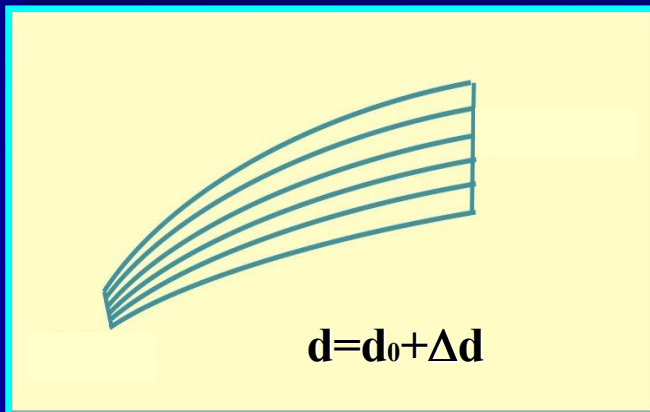
$\beta_{\max} \sim 4$ mrad $= \Omega/2$

Hyperbolic reflecting mirror



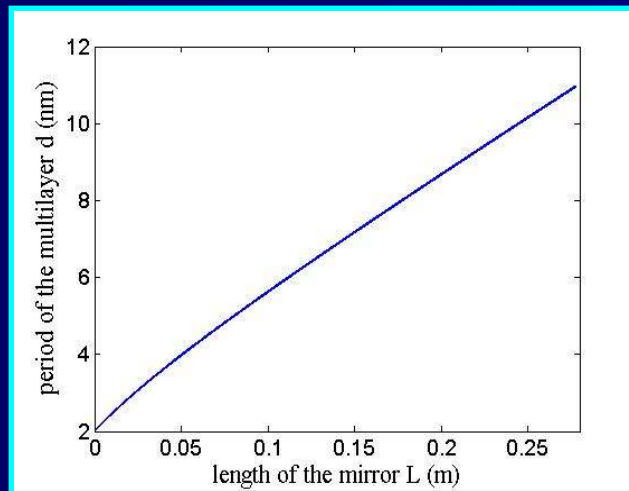
Optical system (hyperbolic)

Critical angle (multilayer):	8-12.5 mrad
Distance source – mirror:	0.2 m
Length of mirrors:	0.25 m
Divergence Φ	16.4 mrad = $2W$
Area of illumination	0.24 m
Acceptance angle:	4 mrad

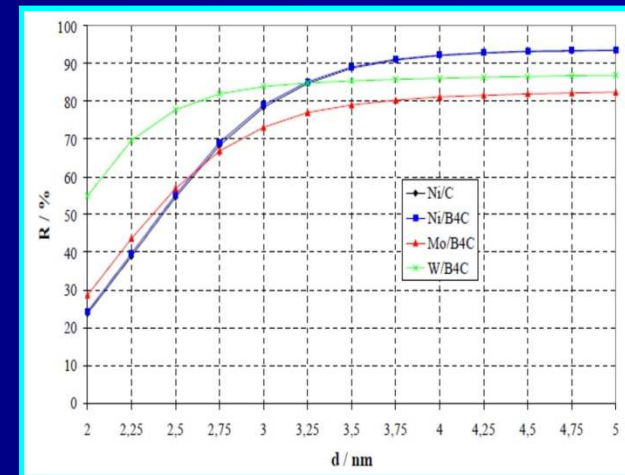


Surface of the mirror is covered by laterally graded multilayers

Laterally graded multilayers

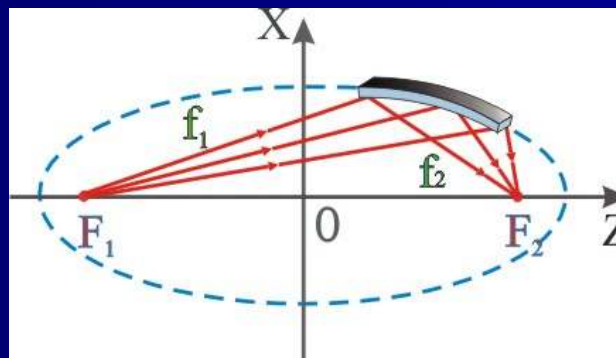
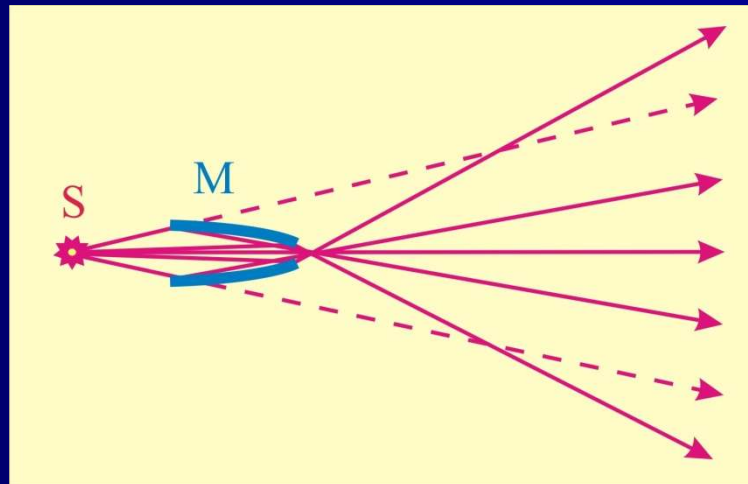


Period of the multilayer increase



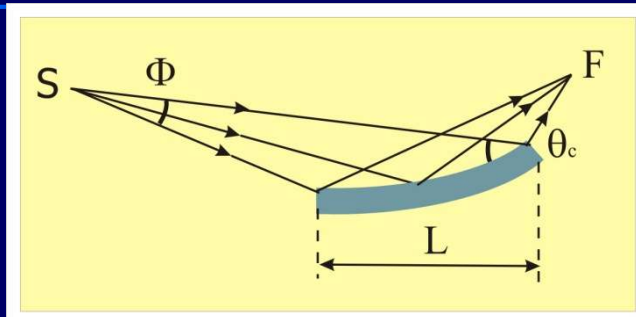
Simulation of the reflectivities of Ni/C, Ni/B4C, Mo/B4C, and W/B4C multilayer systems with 75 periods for E=30 keV radiation
R(d>3.5 nm)->80-90 %

Elliptical focusing mirrors



Elliptical focusing mirrors

Material Pt



$$e_{opt} = 1 - \frac{1}{2} \theta_c^2 M \quad M = \frac{1}{2}$$

$$\Phi_{opt} \approx 5/6 \theta_c M$$

$$L_{opt} \approx 2c \left(1 - \frac{2 - \sqrt{1+M}}{1+M} \right)$$

2 mirror or ellipsoid

Divergence ~16 mrad

Distance source –mirror:	1 m
Critical angle:	3.4 mrad
Acceptance angle (Φ_{opt})	1.4 mrad
Length of the mirrors:	~1 m
Divergence	~ 3mrad

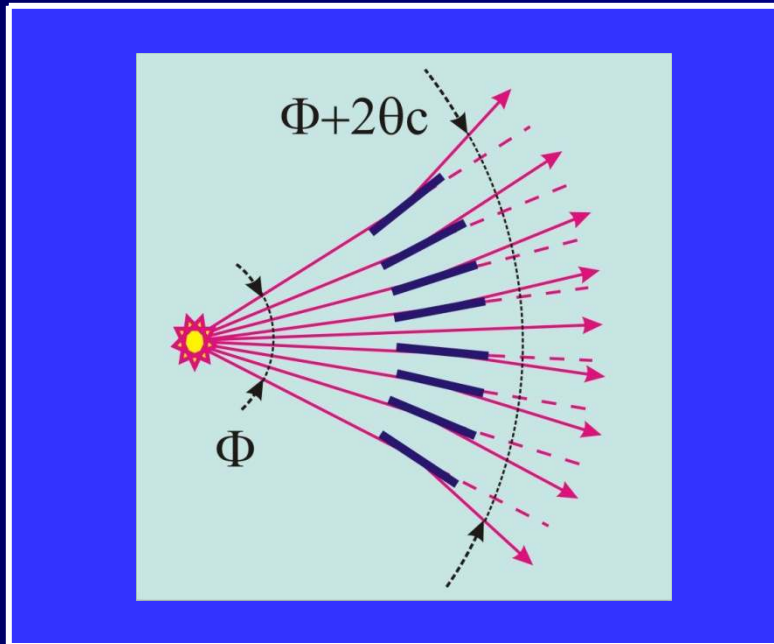
Distance	0.2 m
Acceptance angle	1.4 mrad
Length of the mirror	~0.2m
Divergence	~ 3mrad

Multilayer

Resonance angle (θ_1)	8-12.4 mrad
Acceptance angle (Φ_{opt})	4.6 mrad
Distance	1m
Length of the mirror	0.97 m
Divergence	~ 8-10 mrad

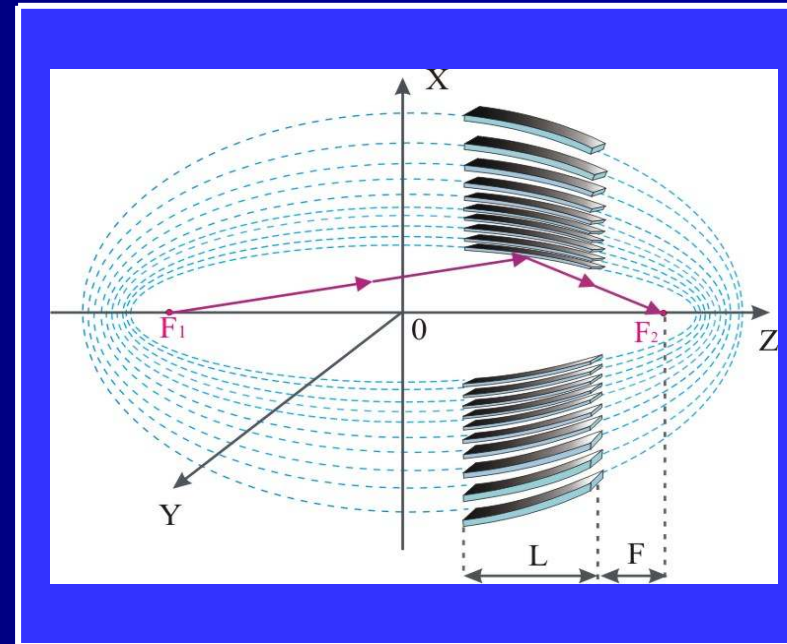
Distance	0.2 m
Acceptance angle (Φ_{opt})	4.6 mrad
Length of the mirror	~0.2 m
Divergence	~ 8-10 mrad

Multiple mirrors



$\theta_c(\text{Pt}) = 3.4 \text{ mrad}$ $\Phi_0 = \Phi + 4\theta \sim 16 \text{ mrad}$
 $D \sim 15\text{m} * 16\text{mrad} \sim 0.24 \text{ m}$

*I. Bukreeva, A. Gerardino, A. Surpi, A. Cedola,
 S. Dabagov, S. Lagomarsino,
 Design and simulation of nested x-ray mirrors,
 Proc. SPIE, vol. 5974 (2005).*

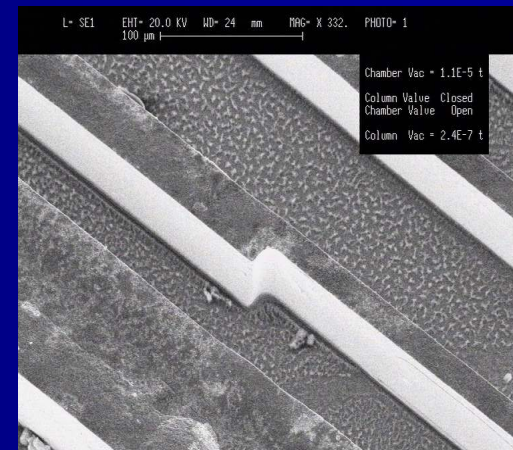
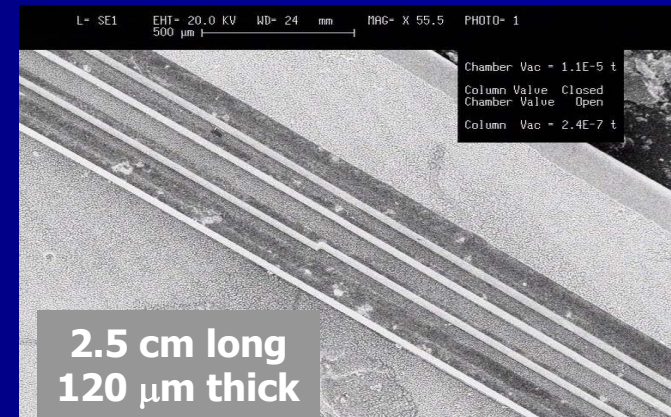


*I. Bukreeva, A. Surpi, A. Gerardino,
 S. Lagomarsino, F. Perennes, M. Altissimo,
 S. Cabrini, A. Carpentiero, A. Vincenzo and
 P. Cavallotti, Multiple micro mirrors for X-ray
 focusing and collimation, Optics Communications,
 259, 366- 372, (2006).*

Experimental results with deep X-ray lithography



- 4 mirror system for synchrotron radiation
- Mirrors in Ni grown by electrochemical deposition



Experimental results with SU8



- Few-centimeter long self-standing mirrors
- No enlargement in the process

